The 8th International Conference on Microelectronics and Plasma Technology | The 9th International Symposium on Functional Materials

Joint International Conference on The 8th ICMAP & The 9th ISFM

January 17-20, 2021 | Online Conference

[WB3] Plasma Diagnostics and Process Monitoring Technology IV	
Date / Time	January 20 (Wed.), 2021 / 13:20-14:40
Place	Channel B
Session Chair(s)	Rodolphe Manchauffé (Jeonbuk Nat'l Univ., Korea)

[WB3-1]

Development and Demonstration of Planar Microwave Probes for Non-Invasive Plasma Density Measurement: the MOLE and TUSI Probe

SiJun Kim¹, SangHo Lee², HaJeong Choi¹, JangJae Lee¹, YoungSeok Lee¹, InHo Seong¹, HanSol Choi¹, JinHo Lee¹, MinSu Choi¹, and ShinJae You¹

¹Chungnam Nat'l Univ., Korea, ²Korea Inst. of Machinery and Materials, Korea

[WB3-2]

Plasma Diagnostic by Optical Emission Spectroscopy on TiN MHM Magnetron Sputtering Byeonghwa Jeong¹, Jaeeun Huh², Dohyun Oh², Sangho Lee², and Geunyoung Yeom¹ ¹Sungkyunkwan Univ., Korea, ²ULVAC KOREA, Ltd., Korea

[WB3-3]

Plasma Information Variable of Electron Temperature (PI-Te) Analysis by Deconvolution of Optical Signals

Jihoon Park¹, Jiwon Kwon¹, Sangwon Ryu¹, Jaemin Song¹, Jihwan Park², Yongjin Kim², and Gon Ho Kim¹ ¹Seoul Nat'l Univ., Korea, ²SK Hynix, Korea

[WB3-4]

Development of Flat Cutoff Probe for Real-time Electron Density Measurement

Hee Jung Yeom¹, Jung Hyung Kim¹, Shin Jae You², and Hyo-Chang Lee¹ ¹KRISS, Korea, ²Chungnam Nat'l Univ., Korea

14:20-14:40

13:20-13:40

13:40-14:00

14:00-14:20